

## Information sheet

**Tool Name:** Four target E-Beam Evaporator

**System Owner:** Mallikarjuna Chary

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**Material that can be deposited:** Aluminium, Titanium, Silver, Palladium

### Limitations / Restrictions:

- This tool is categorized as “**semi clean PV**” tool.
- Only samples which satisfy the “semi -clean PV” requirement will be allowed on this tool.
- Outside samples are to be discussed in Si group meeting and then to be processed inside after approval.
- All the samples processed in it will be considered as Na/K contaminated.

### Samples size:

- **Si** (Minimum size: Quarter of 2 “ wafer, Maximum size: 4 “ wafers).
- Cleaned glass on case-to-case basis.

### Violation policy:

1. If there is any mishandling of the system by the AU and it is not reported to the SO on time by the user : He/she will be barred from using the system for 3 weeks and he/she has to attend consecutive cleaning sessions plus one day to assist the facility team in their work.
2. If one fails to attend 2-3 cleaning sessions consecutively that too with out informing your cleaning partner or SO, one has to attend back to back cleaning sessions for the next two weeks.
3. If the logbook entry is missed, it will be reported as violation.

### Cleaning Protocol for Four-target e-beam evaporator:

1. Use lint free cloth and IPA only.
2. Clean the instrument body, working table with IPA soaked cloth. (To be done carefully).
3. After cleaning, keep all the accessories and tools at proper place and keep the system region neat and clean.
4. Please take help of cleaners wherever necessary.
5. Please take care of the cables and boxes while the cleaner is cleaning the system and the area nearby.